

# Contents

<b>1 Introduction</b> .....	1
1.1 Advantages of Integrated Optics .....	2
1.1.1 Comparison of Optical Fibers with Other Interconnectors .....	3
1.1.2 Comparison of Optical Integrated Circuits with Electrical Integrated Circuits .....	7
1.2 Substrate Materials for Optical Integrated Circuits .....	8
1.2.1 Hybrid Versus Monolithic Approach .....	9
1.2.2 III–V and II–VI Ternary Systems .....	10
1.2.3 Hybrid OIC’s in $\text{LiNbO}_3$ .....	11
1.2.4 Organization of this Book .....	12
Problems .....	15
References .....	15
<b>2 Optical Waveguide Modes</b> .....	17
2.1 Modes in a Planar Waveguide Structure .....	17
2.1.1 Theoretical Description of the Modes of a Three-Layer Planar Waveguide .....	17
2.1.2 Cutoff Conditions .....	20
2.1.3 Experimental Observation of Waveguide Modes .....	21
2.2 The Ray-Optic Approach to Optical Mode Theory .....	25
2.2.1 Ray Patterns in the Three-Layer Planar Waveguide .....	26
2.2.2 The Discrete Nature of the Propagation Constant $\beta$ .....	28
Problems .....	30
References .....	31
<b>3 Theory of Optical Waveguides</b> .....	33
3.1 Planar Waveguides .....	33
3.1.1 The Basic Three-Layer Planar Waveguide .....	33
3.1.2 The Symmetric Waveguide .....	36
3.1.3 The Asymmetric Waveguide .....	38

3.2	Rectangular Waveguides . . . . .	39
3.2.1	Channel Waveguides . . . . .	40
3.2.2	Strip-Loaded Waveguides . . . . .	45
	Problems . . . . .	48
	References . . . . .	49
<b>4</b>	<b>Waveguide Fabrication Techniques . . . . .</b>	<b>53</b>
4.1	Deposited Thin Films . . . . .	53
4.1.1	Sputtered Dielectric Films . . . . .	53
4.1.2	Deposition from Solutions . . . . .	56
4.1.3	Organosilicon Films . . . . .	57
4.2	Substitutional Dopant Atoms . . . . .	57
4.2.1	Diffused Dopants . . . . .	57
4.2.2	Ion Exchange and Migration . . . . .	59
4.2.3	Ion Implantation . . . . .	60
4.3	Carrier-Concentration-Reduction Waveguides . . . . .	62
4.3.1	Basic Properties of Carrier-Concentration-Reduction Waveguides . . . . .	62
4.3.2	Carrier Removal by Proton Bombardment . . . . .	64
4.4	Epitaxial Growth . . . . .	65
4.4.1	Basic Properties of Epitaxially Grown Waveguides . . . . .	65
4.4.2	Ga(1-x)AlxAs Epitaxially Grown Waveguides . . . . .	66
4.4.3	Epitaxial Waveguides in Other III-V and II-VI and IV Materials . . . . .	70
4.4.4	Molecular Beam Epitaxy . . . . .	71
4.4.5	Metal-Organic Chemical Vapor Deposition . . . . .	72
4.5	Electro-Optic Waveguides . . . . .	73
4.6	Oxidation . . . . .	74
4.7	Methods for Fabricating Channel Waveguides . . . . .	75
4.7.1	Ridged Waveguides Formed by Etching . . . . .	75
4.7.2	Strip-Loaded Waveguides . . . . .	77
4.7.3	Masked Ion Implantation, Diffusion or Ion Exchange . . . . .	77
4.7.4	Focused Beam Writing Techniques . . . . .	78
	Problems . . . . .	79
	References . . . . .	81
<b>5</b>	<b>Polymer and Fiber Integrated Optics . . . . .</b>	<b>85</b>
5.1	Types of Polymers . . . . .	85
5.2	Polymer Processing . . . . .	87
5.2.1	Processing of Polystyrene . . . . .	87
5.2.2	Processing of Polyimide . . . . .	89
5.2.3	Post-Deposition Processing . . . . .	89
5.3	Applications of Polymer Waveguide Interconnections . . . . .	90
5.4	Polymer Waveguide Devices . . . . .	93
5.4.1	Passive Polymer Devices . . . . .	93
5.4.2	Active Polymer Devices . . . . .	96

- 5.5 Optical Fiber Waveguide Devices ..... 98
- Problems ..... 103
- References ..... 104
  
- 6 Losses in Optical Waveguides ..... 107**
  - 6.1 Scattering Losses ..... 107
    - 6.1.1 Surface Scattering Loss ..... 108
  - 6.2 Absorption Losses ..... 110
    - 6.2.1 Interband Absorption ..... 110
    - 6.2.2 Free Carrier Absorption ..... 112
  - 6.3 Radiation Losses ..... 116
    - 6.3.1 Radiation Loss from Planar and Straight Channel Waveguides ..... 117
    - 6.3.2 Radiation Loss from Curved Channel Waveguides ..... 117
  - 6.4 Measurement of Waveguide Losses ..... 120
    - 6.4.1 End-Fire Coupling to Waveguides of Different Length ... 120
    - 6.4.2 Prism-Coupled Loss Measurements ..... 122
    - 6.4.3 Scattering Loss Measurements ..... 123
  - Problems ..... 125
  - References ..... 127
  
- 7 Waveguide Input and Output Couplers ..... 129**
  - 7.1 Fundamentals of Optical Coupling ..... 129
  - 7.2 Transverse Couplers ..... 130
    - 7.2.1 Direct Focusing ..... 130
    - 7.2.2 End-Butt Coupling ..... 131
  - 7.3 Prism Couplers ..... 135
  - 7.4 Grating Couplers ..... 139
    - 7.4.1 Basic Theory of the Grating Coupler ..... 139
    - 7.4.2 Grating Fabrication ..... 141
  - 7.5 Tapered Couplers ..... 143
  - 7.6 Tapered Mode Size Converters ..... 144
  - 7.7 Fiber to Waveguide Couplers ..... 145
    - 7.7.1 Butt Coupling ..... 145
    - 7.7.2 High Density Multifiber Connectors ..... 148
  - Problems ..... 149
  - References ..... 151
  
- 8 Coupling Between Waveguides ..... 153**
  - 8.1 Multilayer Planar Waveguide Couplers ..... 153
  - 8.2 Dual-Channel Directional Couplers ..... 154
    - 8.2.1 Operating Characteristics of the Dual-Channel Coupler ..... 155
    - 8.2.2 Coupled-Mode Theory of Synchronous Coupling ..... 157

- 8.2.3 Methods of Fabricating Dual-Channel Directional Couplers ..... 160
- 8.2.4 Applications Involving Directional Couplers ..... 164
- 8.3 Butt-Coupled Ridge Waveguides ..... 164
- 8.4 Branching Waveguide Couplers ..... 164
- 8.5 Optical Fiber Couplers and Splitters ..... 166
- Problems ..... 167
- References ..... 168
  
- 9 Electro-Optic Modulators ..... 171**
  - 9.1 Basic Operating Characteristics of Switches and Modulators ..... 171
    - 9.1.1 Modulation Depth ..... 171
    - 9.1.2 Bandwidth ..... 172
    - 9.1.3 Insertion Loss ..... 172
    - 9.1.4 Power Consumption ..... 173
    - 9.1.5 Isolation ..... 173
  - 9.2 The Electro-Optic Effect ..... 174
  - 9.3 Single-Waveguide Electro-Optic Modulators ..... 175
    - 9.3.1 Phase Modulation ..... 175
    - 9.3.2 Polarization Modulation ..... 177
    - 9.3.3 Intensity Modulation ..... 177
    - 9.3.4 Electro-Absorption Modulation ..... 178
  - 9.4 Dual-Channel Waveguide Electro-Optic Modulators ..... 181
    - 9.4.1 Theory of Operation ..... 181
    - 9.4.2 Operating Characteristics of Dual-Channel Modulators .. 183
  - 9.5 Mach-Zehnder Type Electro-Optic Modulators ..... 187
  - 9.6 Electro-Optic Modulators Employing Reflection or Diffraction ... 188
    - 9.6.1 Bragg-Effect Electro-Optic Modulators ..... 188
    - 9.6.2 Electro-Optic Reflection Modulators ..... 190
  - 9.7 Comparison of Waveguide Modulators to Bulk Electro-Optic Modulators ..... 191
  - 9.8 Traveling Wave Electrode Configurations ..... 193
  - Problems ..... 195
  - References ..... 198
  
- 10 Acousto-Optic Modulators ..... 201**
  - 10.1 Fundamental Principles of the Acousto-Optic Effect ..... 201
  - 10.2 Raman-Nath-Type Modulators ..... 203
  - 10.3 Bragg-Type Modulators ..... 204
  - 10.4 Bragg-Type Beam Deflectors and Switches ..... 208
  - 10.5 Performance Characteristics of Acoustic-Optic Modulators and Beam Deflectors ..... 210
  - 10.6 Accusto-Optic Frequency Shifters ..... 214
  - Problems ..... 217
  - References ..... 219

- 11 Basic Principles of Light Emission in Semiconductors** . . . . . 221
  - 11.1 A Microscopic Model for Light Generation and Absorption in a Crystalline Solid . . . . . 221
    - 11.1.1 Basic Definitions . . . . . 221
    - 11.1.2 Conservation of Energy and Momentum . . . . . 224
  - 11.2 Light Emission in Semiconductors . . . . . 226
    - 11.2.1 Spontaneous Emission . . . . . 226
    - 11.2.2 Stimulated Emission . . . . . 232
  - 11.3 Lasing . . . . . 234
    - 11.3.1 Semiconductor Laser Structures . . . . . 235
    - 11.3.2 Lasing Threshold . . . . . 235
    - 11.3.3 Efficiency of Light Emission . . . . . 237
  - Problems . . . . . 238
  - References . . . . . 239
  
- 12 Semiconductor Lasers** . . . . . 241
  - 12.1 The Laser Diode . . . . . 241
    - 12.1.1 Basic Structure . . . . . 241
    - 12.1.2 Optical Modes . . . . . 242
    - 12.1.3 Lasing Threshold Conditions . . . . . 243
    - 12.1.4 Output Power and Efficiency . . . . . 248
  - 12.2 The Tunnel-Injection Laser . . . . . 250
    - 12.2.1 Basic Structure . . . . . 250
    - 12.2.2 Lasing Threshold Conditions . . . . . 252
  - 12.3 Polymer Lasers . . . . . 252
  - 12.4 New Semiconductor Materials for New Wavelengths . . . . . 253
    - 12.4.1 Gallium Nitride Lasers . . . . . 253
    - 12.4.2 Silicon Lasers . . . . . 254
  - Problems . . . . . 255
  - References . . . . . 257
  - Supplementary Reading on Semiconductor-Laser Fundamentals . . . . . 258
  
- 13 Optical Amplifiers** . . . . . 259
  - 13.1 Optical Fiber Amplifiers . . . . . 259
    - 13.1.1 Erbium Doped Fiber Amplifiers . . . . . 260
    - 13.1.2 Raman Optical Fiber Amplifiers . . . . . 263
    - 13.1.3 Other Optical Fiber Amplifiers . . . . . 264
  - 13.2 Non-Fiber Ion-Doped Optical Amplifiers . . . . . 265
  - 13.3 Semiconductor Optical Amplifiers . . . . . 265
    - 13.3.1 Integrated Semiconductor Optical Amplifiers . . . . . 268
  - 13.4 Comparison of Ion-Doped Fiber Amplifiers with SOAs . . . . . 269
    - 13.4.1 Wavelength Range . . . . . 269
    - 13.4.2 Performance Characteristics . . . . . 269
  - 13.5 Gain Equalization . . . . . 271
  - 13.6 Fiber Lasers . . . . . 271

Problems .....	273
References .....	274
Supplementary Reading on Optical Amplifiers .....	275
<b>14 Heterostructure, Confined-Field Lasers .....</b>	<b>277</b>
14.1 Basic Heterojunction Laser Structures .....	278
14.1.1 Single Heterojunction (SH) Lasers .....	278
14.1.2 Double Heterostructure (DH) Lasers .....	279
14.2 Performance Characteristics of the Heterojunction Laser .....	280
14.2.1 Optical Field Confinement .....	280
14.2.2 Carrier Confinement .....	283
14.2.3 Comparison of Laser Emission Characteristics .....	284
14.3 Control of Emitted Wavelength .....	285
14.3.1 Ga <sub>(1-x)</sub> Al <sub>x</sub> As Lasers for Fiber-Optic Applications .....	285
14.3.2 Lasers Made of Quaternary Materials .....	287
14.3.3 Long-Wavelength Lasers .....	287
14.4 Advanced Heterojunction Laser Structures .....	288
14.4.1 Stripe Geometry Lasers .....	288
14.4.2 Single-Mode Lasers .....	288
14.4.3 Integrated Laser Structures .....	291
14.5 Reliability .....	295
14.5.1 Catastrophic Failure .....	295
14.5.2 Gradual Degradation .....	296
14.6 Vertical Cavity Lasers .....	296
Problems .....	298
References .....	299
Supplementary Reading on Heterojunction Lasers .....	301
<b>15 Distributed-Feedback Lasers .....</b>	<b>303</b>
15.1 Theoretical Considerations .....	303
15.1.1 Wavelength Dependence of Bragg Reflections .....	303
15.1.2 Coupling Efficiency .....	305
15.1.3 Lasing with Distributed Feedback .....	308
15.2 Fabrication Techniques .....	309
15.2.1 Effects of Lattice Damage .....	310
15.2.2 Grating Location .....	310
15.2.3 DBR Lasers .....	313
15.3 Performance Characteristics .....	315
15.3.1 Wavelength Selectability .....	315
15.3.2 Optical Emission Linewidth .....	317
15.3.3 Stability .....	317
15.3.4 Commercially Available DFB Lasers .....	319
15.4 Nanoscale DFB Lasers .....	319
15.4.1 Semiconductor Air Bragg Reflector Lasers .....	320
15.4.2 Quantum Dot DFB Lasers .....	321

Problems ..... 321

References ..... 322

**16 Direct Modulation of Semiconductor Lasers** ..... 325

16.1 Basic Principles of Direct Modulation ..... 325

    16.1.1 Amplitude Modulation ..... 325

    16.1.2 Pulse Modulation ..... 328

    16.1.3 Frequency Modulation ..... 330

16.2 Microwave Frequency Modulation of Laser Diodes ..... 331

    16.2.1 Summary of Early Experimental Results ..... 332

    16.2.2 Factors Limiting Modulation Frequency ..... 332

    16.2.3 Design of Laser Diode Packages for Microwave  
Modulation ..... 336

16.3 Monolithically Integrated Direct Modulators ..... 337

16.4 Amplified Laser Modulation ..... 339

16.5 Direct Modulation of Quantum Dot Lasers ..... 339

16.6 Future Prospects for Microwave Modulation  
of Laser Diodes ..... 340

Problems ..... 340

References ..... 342

Supplementary Reading on Modulation of Laser Diodes ..... 344

**17 Integrated Optical Detectors** ..... 345

17.1 Depletion Layer Photodiodes ..... 345

    17.1.1 Conventional Discrete Photodiodes ..... 345

    17.1.2 Waveguide Photodiodes ..... 348

    17.1.3 Effects of Scattering and Free-Carrier Absorption ..... 349

17.2 Specialized Photodiode Structures ..... 350

    17.2.1 Schottky-Barrier Photodiode ..... 351

    17.2.2 Avalanche Photodiodes ..... 351

    17.2.3 p-i-n Photodiodes ..... 353

    17.2.4 Metal-Semiconductor-Metal Photodiodes ..... 354

17.3 Techniques for Modifying Spectral Response ..... 355

    17.3.1 Hybrid Structures ..... 355

    17.3.2 Heteroepitaxial Growth ..... 356

    17.3.3 Proton Bombardment ..... 360

    17.3.4 Electro-Absorption ..... 363

17.4 Factors Limiting Performance of Integrated Detectors ..... 366

    17.4.1 High Frequency Cutoff ..... 366

    17.4.2 Linearity ..... 367

    17.4.3 Noise ..... 367

Problems ..... 368

References ..... 371

**18 Quantum-Well Devices** . . . . . 375

18.1 Quantum Wells and Superlattices . . . . . 375

18.2 Quantum-Well Lasers . . . . . 377

    18.2.1 Single-Quantum-Well Lasers . . . . . 377

    18.2.2 Multiple Quantum Well Lasers . . . . . 380

18.3 Quantum-Well Modulators and Switches . . . . . 384

    18.3.1 Electro-Absorption Modulators . . . . . 384

    18.3.2 Electro-Optic Effect in Quantum Wells . . . . . 388

    18.3.3 Multiple Quantum Well Switches . . . . . 390

18.4 Quantum-Well Detectors . . . . . 392

    18.4.1 Photoconductive Detectors . . . . . 392

    18.4.2 MQW Avalanche Photodiodes . . . . . 392

18.5 Self-Electro-Optic Effect Devices . . . . . 393

18.6 Quantum-Well Devices in OEIC's . . . . . 394

    18.6.1 Integrated Laser/Modulators . . . . . 395

    18.6.2 A Four-Channel Transmitter Array  
        with MQW Lasers . . . . . 396

Problems . . . . . 398

References . . . . . 399

Supplementary Reading on Quantum Wells . . . . . 401

**19 Micro-Optical-Electro-Mechanical Devices** . . . . . 403

19.1 Basic Equations of Mechanics . . . . . 404

    19.1.1 Axial Stress and Strain . . . . . 404

    19.1.2 Thin Membranes . . . . . 405

    19.1.3 Cantilever Beams . . . . . 406

    19.1.4 Torsion Plates . . . . . 407

19.2 Thin Membrane Devices . . . . . 408

19.3 Cantilever Beam Devices . . . . . 411

19.4 Torsional Devices . . . . . 413

19.5 Optical Elements . . . . . 417

19.6 Future Directions in MOEMS Development . . . . . 418

19.7 Mechanical Properties of Silicon . . . . . 419

Problems . . . . . 419

References . . . . . 420

**20 Applications of Integrated Optics and Current Trends** . . . . . 423

20.1 Applications of Optical Integrated Circuits . . . . . 423

    20.1.1 RF Spectrum Analyzer . . . . . 423

    20.1.2 Monolithic Wavelength-Multiplexed Optical Source . . . . . 426

    20.1.3 Analog-to-Digital Converter (ADC) . . . . . 428

    20.1.4 Integrated-Optic Doppler Velocimeter . . . . . 429

    20.1.5 An IO Optical Disk Readhead . . . . . 430

    20.1.6 OIC Temperature Sensor . . . . . 432

    20.1.7 IO High Voltage Sensor . . . . . 433



20.1.8	IO Wavelength Meters and Spectrum Analyzers . . . . .	434
20.1.9	IO Chemical Sensors . . . . .	435
20.2	Opto-Electronic Integrated Circuits . . . . .	436
20.2.1	An OEIC Transmitter . . . . .	436
20.2.2	An OEIC Receiver . . . . .	437
20.2.3	An OEIC Phased-Array Antenna Driver . . . . .	438
20.3	Devices and Systems for Telecommunications . . . . .	439
20.3.1	Trends in Optical Telecommunications . . . . .	439
20.3.2	New Devices for Telecommunications . . . . .	444
	Problems . . . . .	447
	References . . . . .	447
<b>21</b>	<b>Photonic and Microwave Wireless Systems . . . . .</b>	<b>451</b>
21.1	Merging of Photonics and Microwave Technology . . . . .	451
21.2	Fiber-Optic Transmission of RF and Microwave Signals . . . . .	453
21.2.1	Basic Principles . . . . .	454
21.2.2	Device Performance . . . . .	456
21.2.3	System Performance . . . . .	458
21.3	Microwave Carrier Generation by Optical Techniques . . . . .	459
21.4	Future Projections . . . . .	463
	Problems . . . . .	464
	References . . . . .	465
<b>22</b>	<b>Nanophotonics . . . . .</b>	<b>469</b>
22.1	Dimensions . . . . .	469
22.2	Properties of Electrons and Photons . . . . .	469
22.3	Confinement of Photons and Electrons . . . . .	471
22.4	Photonic Crystals . . . . .	472
22.4.1	Classes of Photonic Crystals . . . . .	472
22.4.2	Comparison of Electrons in Semiconductor Crystals to Photons in Photonic Crystals . . . . .	473
22.5	Fabrication of Nanostructures . . . . .	477
22.5.1	Molecular Beam Epitaxy . . . . .	478
22.5.2	Metalorganic Vapor Phase Epitaxy . . . . .	478
22.5.3	Nanoscale Lithography . . . . .	479
22.5.4	Nanomachining . . . . .	481
22.6	Characterization and Evaluation of Nanostructures . . . . .	485
22.6.1	Available Tools . . . . .	485
22.6.2	Scanning Electron Microscope . . . . .	485
22.6.3	Reflection High-Energy Electron Diffraction . . . . .	486
22.7	Nanophotonic Devices . . . . .	487
22.7.1	Waveguides . . . . .	487
22.7.2	Couplers . . . . .	491
22.7.3	Resonators . . . . .	493
22.7.4	Light Emitters . . . . .	495

22.7.5	Photodetectors .....	496
22.7.6	Sensors .....	497
22.8	Future Projections for Integrated Optics and Nanophotonics .....	499
	Problems .....	501
	References .....	501
<b>Index</b>	.....	<b>507</b>